

Date Searched: 6/22/2008

Databases Searched: USPAT, USPGPUB

Plurals: ON

Terms Searched:

L1 (mask\$3 or exposure or ebeam) near3 (data or pattern)
L2 (sort\$3 or order\$3 or priorit\$8) near15 1 near15 (field or scanstrip)
L3 716/19-21.ccls. or "707"/\$.ccls. or 700/117-121.ccls. or 250/492.1-492.3.ccls. or 430/4-5.ccls. or 378/34-35.ccls.
L4 2 and 3
Results: 43 hits

L5 (arrang\$6 or plac\$6) near15 1 near15 (field or scanstrip)
L6 3 and 5
Results: 71 hits

L7 raster\$8
L8

Mizuno; Fumio et al.	US 6757621 B2	USPAT 702/35
Bennett; John R. et al.	US 6675169 B1	USPAT 707/101
Kondo; Makoto	US 6597002 B1	USPAT 250/492.2
Langston; Joseph C. et al.	US 6051344 A	USPAT 430/5
Enichen; William A. et al.	US 6040095 A	USPAT 430/5
Nakao; Shuji	US 5962172 A	USPAT 430/5
Okino; Teruaki	US 5874198 A	USPAT 430/296
Manabe; Yasuo et al.	US 6350992 B1	USPAT 250/492.22
Muraki; Masato	US 6104035 A	USPAT 250/492.22
Suzuki; Shohei	US 6087669 A	USPAT 250/492.23
Manabe; Yasuo et al.	US 6060717 A	USPAT 250/492.22
Kusonose; Haruhiko et al.	US 5296917 A	USPAT 356/401
Frei; Joseph B.	US 5189306 A	USPAT 250/492.2
Tojo; Toru et al.	US 4572956 A	USPAT 250/492.2
Komatsuda, Hideki	US 20040084632 A1	US-PGPUB 250/492.2
Nakasuij; Mamoru et al.	US 6194102 B1	USPAT 430/5
Sohda; Yasunari et al.	US 5387799 A	USPAT 250/492.2
Ebinuma; Ryuichi et al.	US 5365561 A	USPAT 378/34
Isaacson; Michael et al.	US 4659429 A	USPAT 216/24

**With rasterization:

Muraki; Masato US 6104035 A
Kusonose; Haruhiko et al. US 5296917 A
Isaacson; Michael et al. US 4659429 A
Nakao; Shuji US 5962172 A

Databases Searched: EPO, JPO, IBM TDB, Derwent

Plurals: ON

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L2 (sort\$3 or order\$3 or priorit\$8 or arrang\$6 or plac\$6) near15 1 near15 (field or scanstrip)
Results: 71 hits

KOYAMA, MASAAKI JP 11087223 A

OSHIMA, TORU JP 09162101 A
WATANABE, TAKASHI JP 06310410 A
MIYAJIMA, MASAAKI JP 04288813 A
KUSUSE, HARUHIKO et al. JP 04237115 A
NAKASUJI M JP 11054392 A
HOSHINO H et al. JP 08321462 A
MANABE Y JP 07263323 A

HAYAKAWA, YOSHIHIRO JP 09293661 A
YODA, HARUO et al. EP 1387389 A2

Database Searched: IEE/IEEE Xplore

Terms Searched: (mask* or exposure or ebeam) <near/3> (data or pattern) <near/15>
(sort* or order* or priorit* or arrang* or plac*) <near/15> (field or scanstrip)

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